

# The SPI Supplies Family of Instruments



**SPI-MODULE™**  
Sputter/Carbon Coater Module



**PlasmaPrep III™ Plasma Etcher**  
with **PPIII Process Controller**



**SPI-Vacu Prep II™**  
Turbo Pump Evaporation System



**Gentle Mill™**  
Ion Milling System



**PlasmaPrep X™**  
Parallel Plate Plasma Etcher



**Osmium Plasma Coaters**  
for FESEM Applications



**SPI-DRY™**  
Critical Point Dryer



**PlasmaPrep III™ Solid State**  
Plasma Cleaner for cleaning TEM holders

100nm

Excellence in sample preparation is just a click away.  
[2spi.com](http://2spi.com)

Your results will never be better than your sample preparation.  
See how SPI Supplies can help you deliver the highest quality results for all your  
SEM/EDS, TEM and FESEM applications.



**SPI Supplies** Division of **STRUCTURE PROBE, Inc.**

P.O. Box 656 • West Chester, PA 19381-0656 USA  
Phone: 1-610-436-5400 • 1-800-2424-SPI (USA and Canada) • Fax: 1-610-436-5755 • [2spi.com](http://2spi.com) • E-mail: [sales@2spi.com](mailto:sales@2spi.com)





## *SPI Supplies Family of Instruments*

### *SPI Module™ Sputter/Carbon Coaters*

*Combination sputter/carbon coater system for everyday routine SEM/EDS sample preparation. Fast and easy to use.*

### *Plasma Prep III™*

*Solid state compact tabletop design with RF power range of 1 to 100W. The Plasma Prep III™ Process Controller is an add-on module with multiple gas inputs and process timer control.*

### *SPI Supplies Vacu Prep II™*

*Fast, clean, efficient, turbo-pump, high vacuum bench-top evaporator with simple automated operation for evaporation or sputtering.*

### *Gentle Mill Ion Beam Workstation*

*Ion Mill system for the highest quality and damage free XTEM, HRTEM or STEM samples.*

### *SPI PlasmaPrep X™ Parallel Plate Plasma Etcher*

*The parallel plate design of an anisotropic etcher permits the removal of a passivation layer without any undercutting.*

### *Osmium Plasma Coaters*

*The must have coater for high resolution FE-SEM work. Typical thickness of 1nm to 3nm of osmium metal, with excellent electrical and thermal conductivity and a virtually "amorphous" grain size coating.*

### *SPI-Dry™ Critical Point Dryers*

*Used in applications in electron microscopy as well as preparation of aerogels and MEMS. The method enables the drying of samples without collapsing or deforming the structure of wet, fragile specimens.*

### *SPI Plasma Prep III™ Plasma Cleaner*

*Compact bench-top sized plasma cleaner, that uses the "dry plasma process" for the removal of contamination on TEM specimen stages.*

**SPI Supplies** Division of **STRUCTURE PROBE, Inc.**

P.O. Box 656 • West Chester, PA 19381-0656 USA

Phone: 1-610-436-5400 • 1-800-2424-SPI (USA and Canada) • Fax: 1-610-436-5755 • E-mail: sales@2spi.com

**2spi.com**